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Applicant

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1011 U.S. PAT.  
NO. 600376  
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## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
Ed	5,447,890	09/1995	Kato et al.	437	249	

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
Ed	EP 0782179	7/02/1997	EPO			X	
	EP 0337556	10/18/1989	EPO			X	
	WO 8912318	12/14/1989	PCT			X	
	EP 0784976	03/28/1997	EPO			X	
Ed	JP06-114664	04/26/1994	JAPAN				Abstract

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Ed Current Status of 200 mm and 300 mm Silicon Wafers; Howard R. Huff et al.; 1998 Publication Board, Japanese Journal of Applied Physics; vol. 37, part 1, No. 3B March 1998; pp 1210-1216;

Ed Thickness Considerations in Direct Silicon Wafer Bonding; Q.Y. Tong et al., J. Electrochem. Soc., Vol. 142, No. 11; November 1995

EXAMINER	Ed	DATE CONSIDERED	5/14/03
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 809; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.			